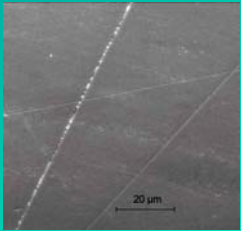


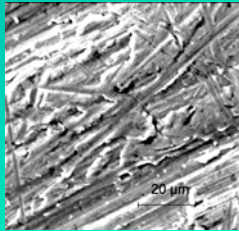
Methods for the physical and chemical characterisation of surfaces of titanium implants

Surface modifications of titanium implants

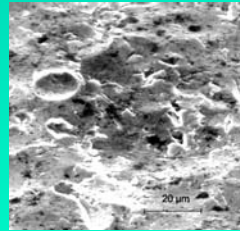
Polished (P)



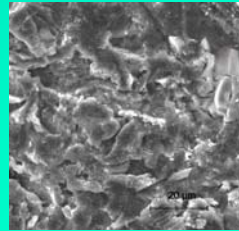
Machined (M)



Glass-particle blasted (G)



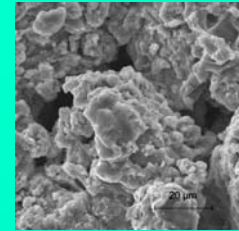
Corundum-blasted 2,5 bar (C2.5)



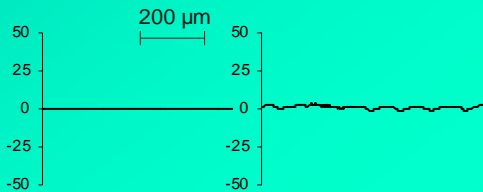
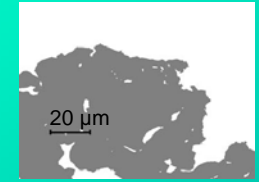
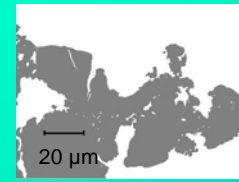
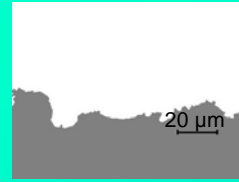
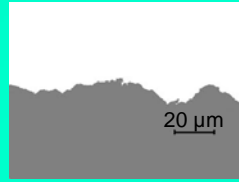
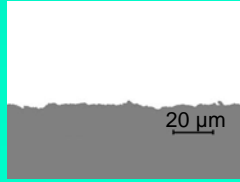
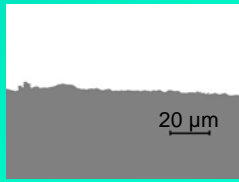
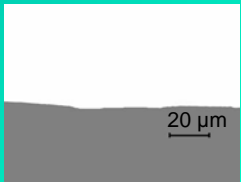
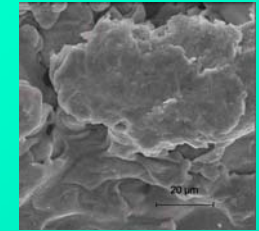
Corundum-blasted 6 bar (C6)



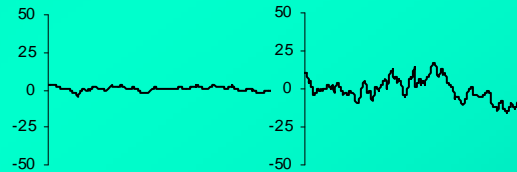
Vacuum-plasma sprayed rough (VR)



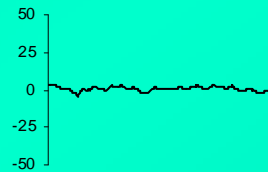
Vacuum-plasma sprayed fine (VF)



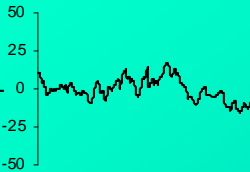
$R_a=0.07\mu\text{m}$



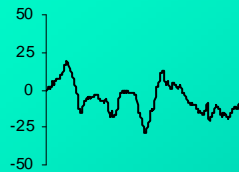
$R_a=0.53\mu\text{m}$



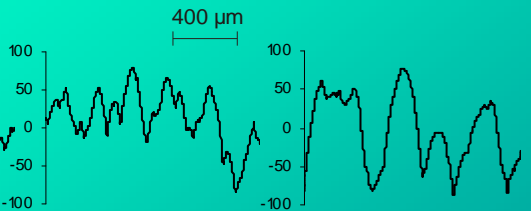
$R_a=1.22\mu\text{m}$



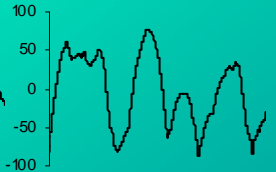
$R_a=4.12\mu\text{m}$



$R_a=6.07\mu\text{m}$



$R_a=20.99\mu\text{m}$



$R_a=48.59\mu\text{m}$

Commercial distributed implants do not have an uniform surface:
--> every part of the implant needs an **optimized** surface

Complete and exact
description of titanium surfaces with different roughness

Searching for relevant parameters for a correlation
physico-chemical characteristics --> cell behaviour
--> biocompatibility

(1) Estimation of the “true” surface area

quality control, input parameter for further working steps
in modifying the implant surface:

- electrochemical deposition of hydroxyapatite
- embedding of antibiotic substances

3 electrochemical methods:

- Electrochemical Impedance Spectroscopy (EIS)
- Linear Sweep Voltammetry (LSV)
- Chronoamperometry (CA)

(2) Characterisation of the surface roughness

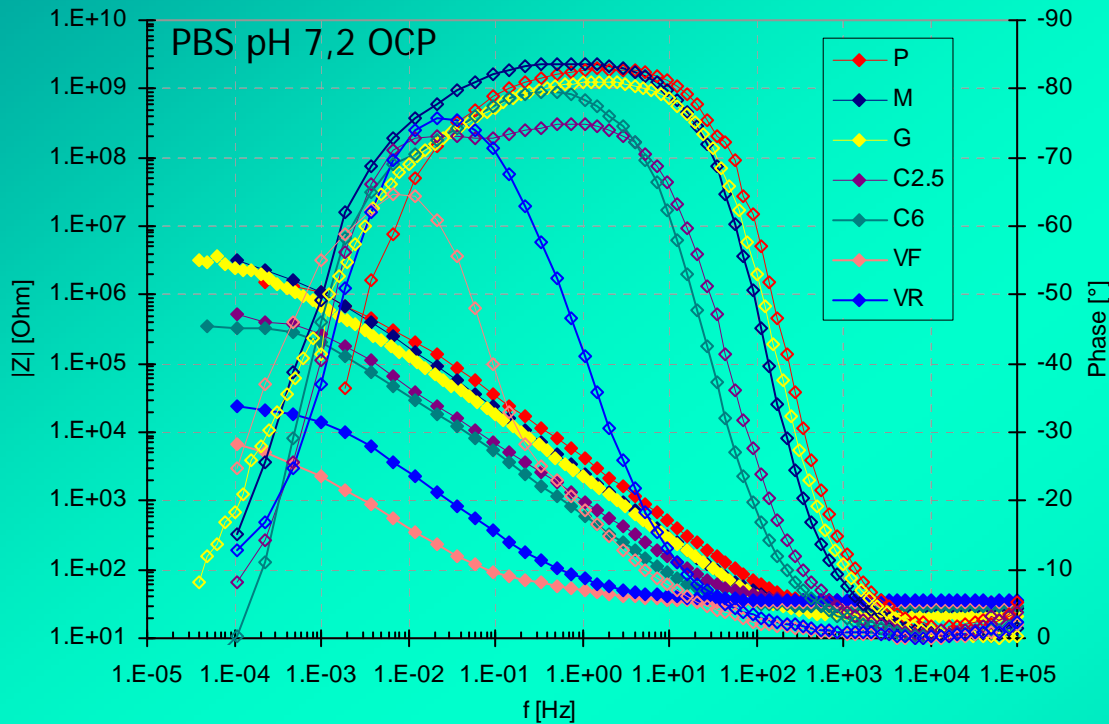
with the parameter **fractal dimension D_F**

- 2 electrochemical methods: EIS and LSV
- comparison with results of Digital Image Processing (DIP)

(3) Cell biological tests

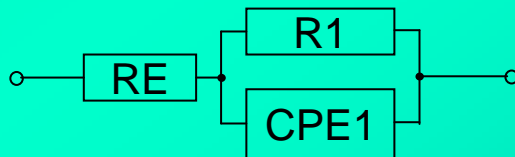
Electrochemical Impedance Spectroscopy (EIS)

Bode plot for all investigated titanium surfaces

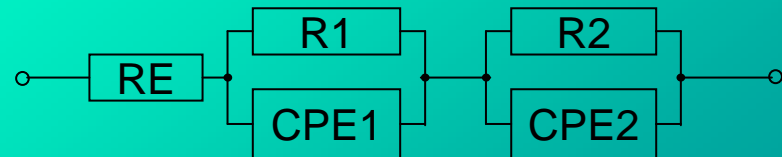


modification	Capacity C of the CPE [μF]
P	38.34
M	67.37
G	78.51
C2.5	170.34
C6	264.06
VF	6334.16
VR	4807.91

P, M, G, C2.5, C6

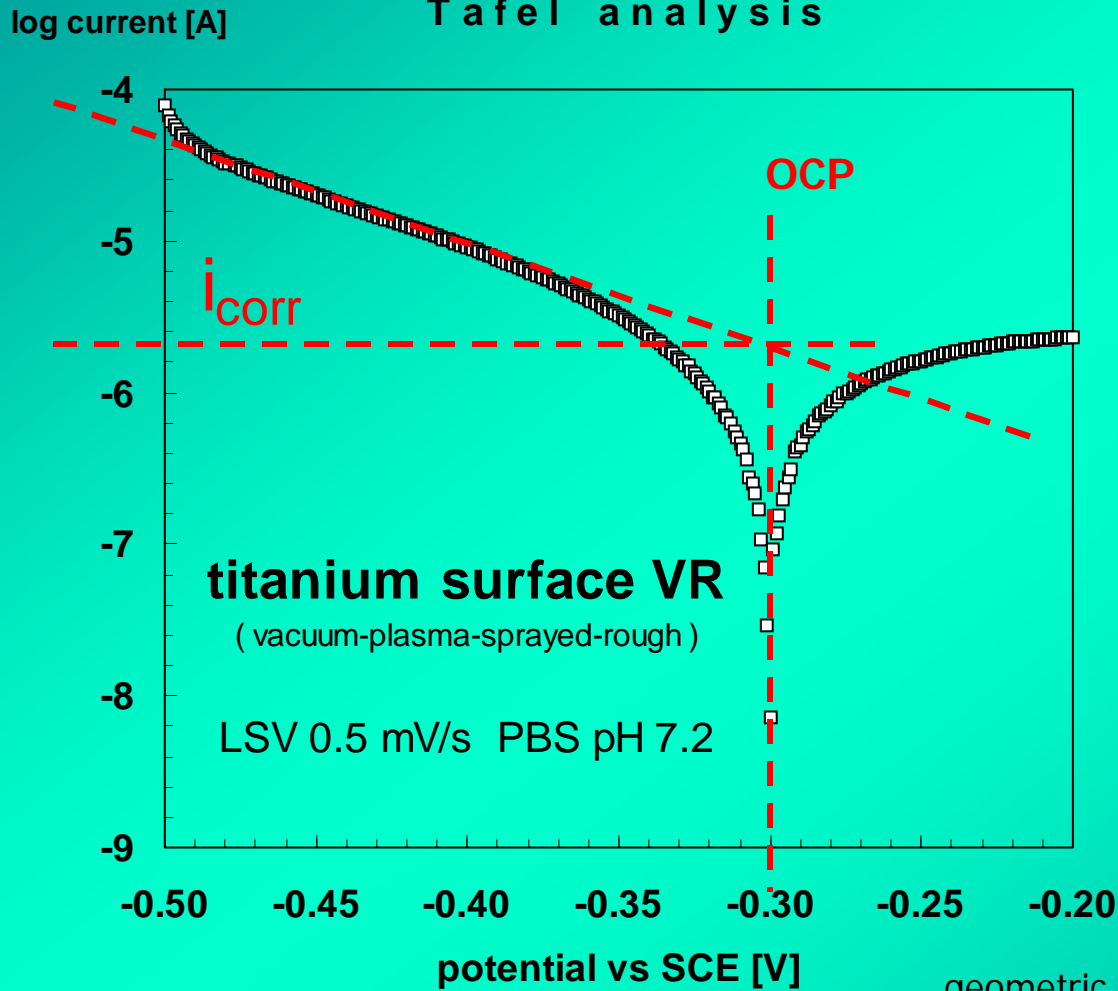


VF, VR



Linear Sweep Voltammetry (LSV)

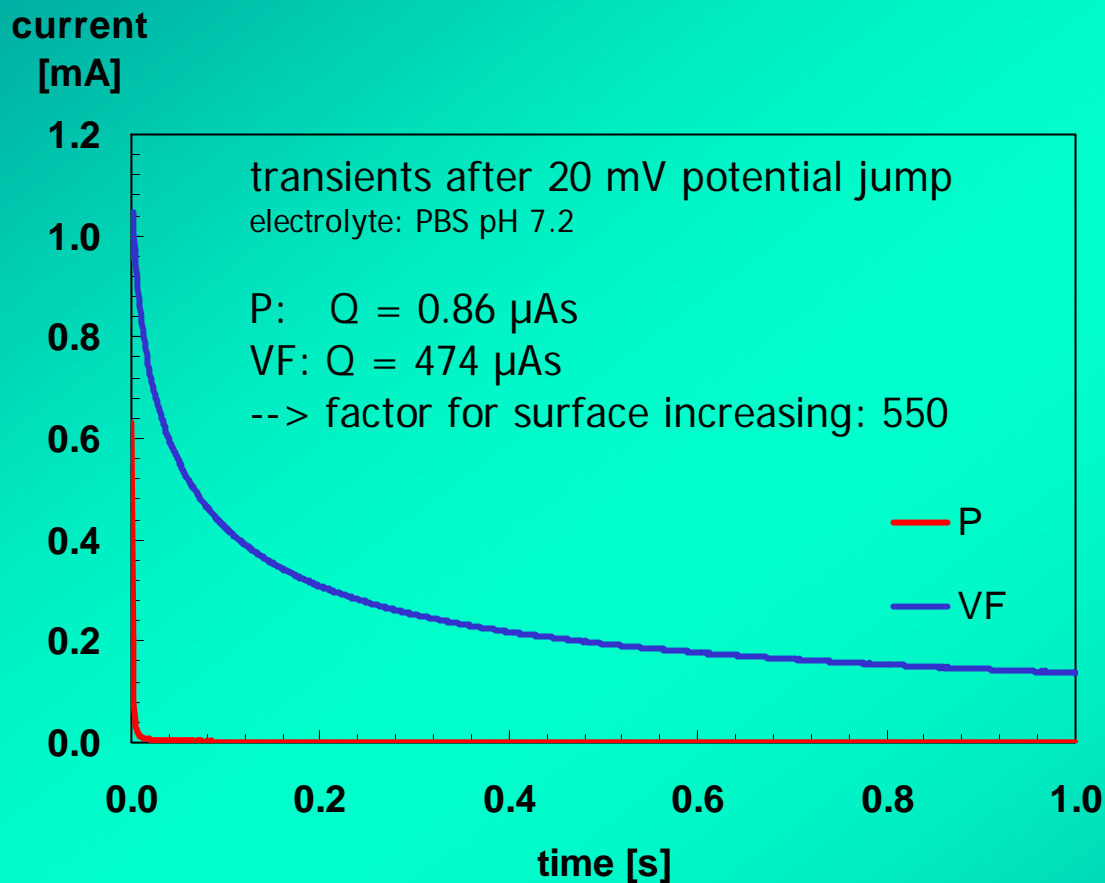
Tafel analysis



geometric area : 2.27 cm²

modification	I_{corr} [nA]
P	13
M	16
G	37
C2.5	51
C6	341
VF	7294
VR	1740

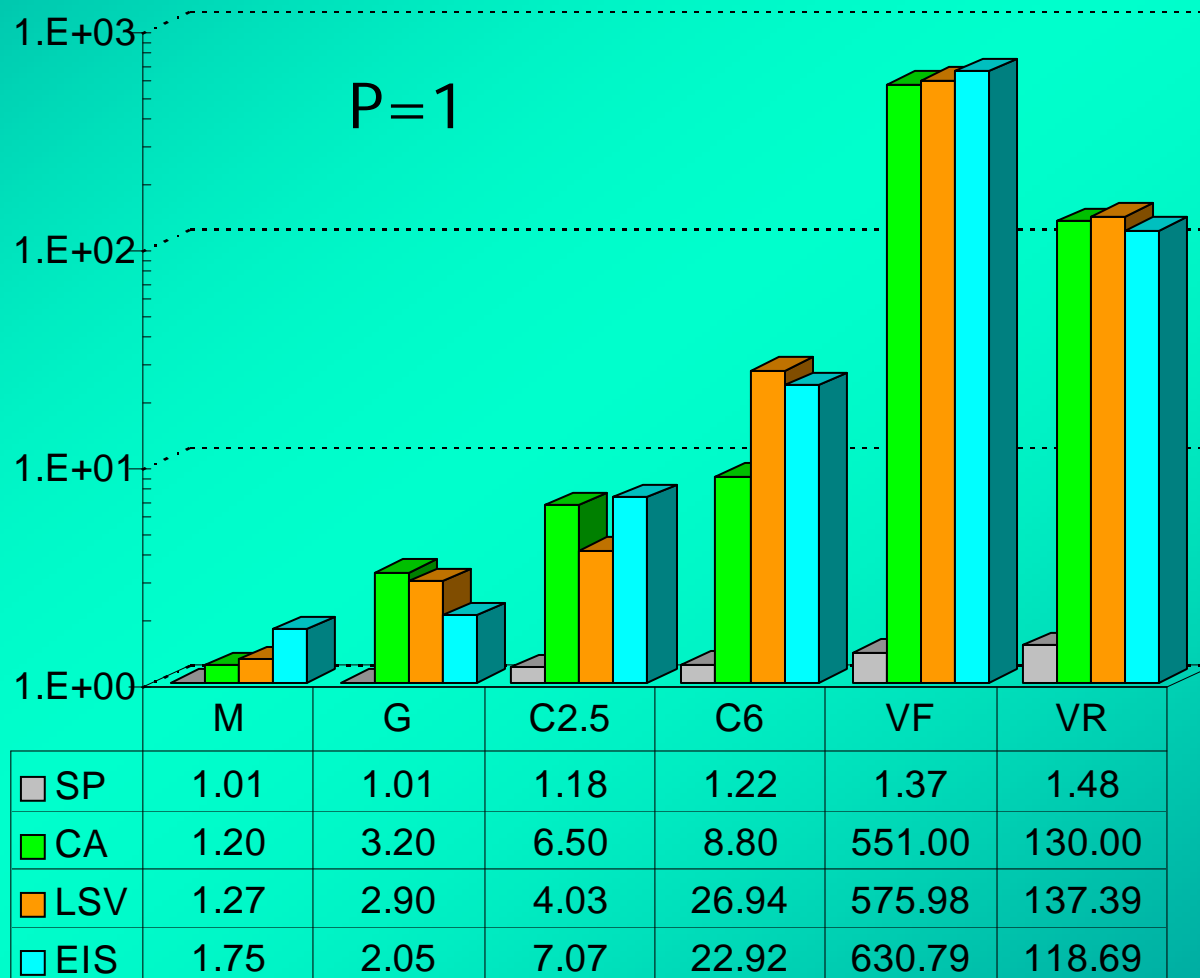
Chronoamperometry (CA)



geometric area : 2.27 cm²

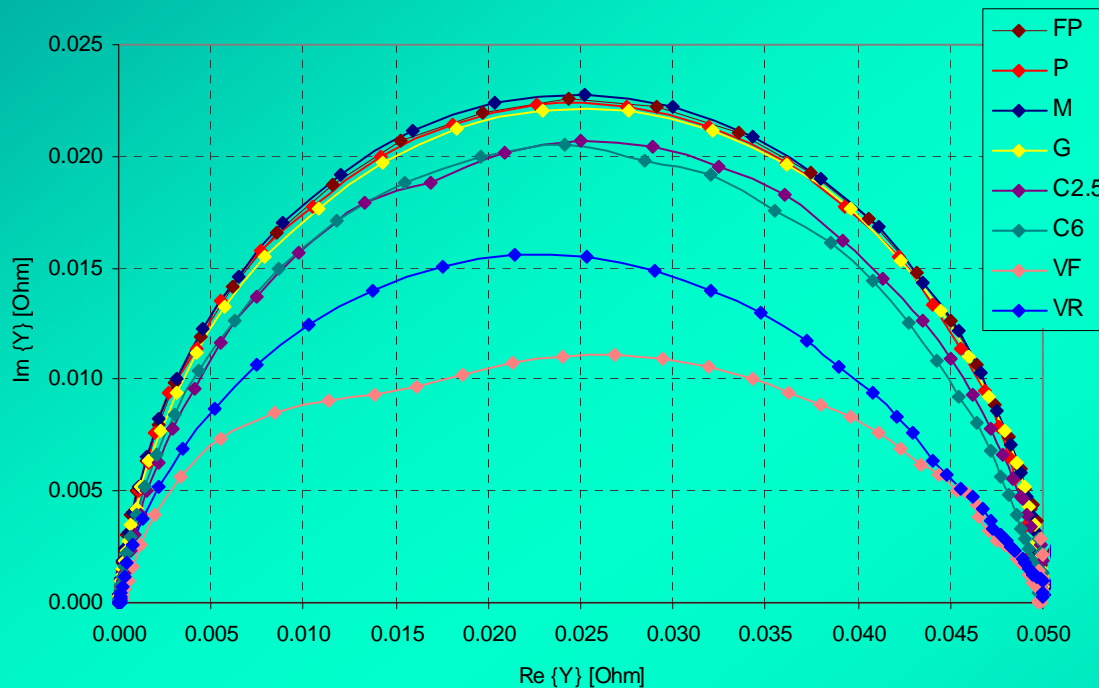
modification	Q [μC]
P	0.86
M	1.03
G	2.75
C2.5	5.59
C6	7.57
VF	474.00
VR	112.00

Increasing of the electroactive area obtained by three electrochemical methods (EIS, LSV, CA) in comparison to that obtained by surface profiling



Determination of the fractal dimension D_F by EIS

Admittance plot for all modifications



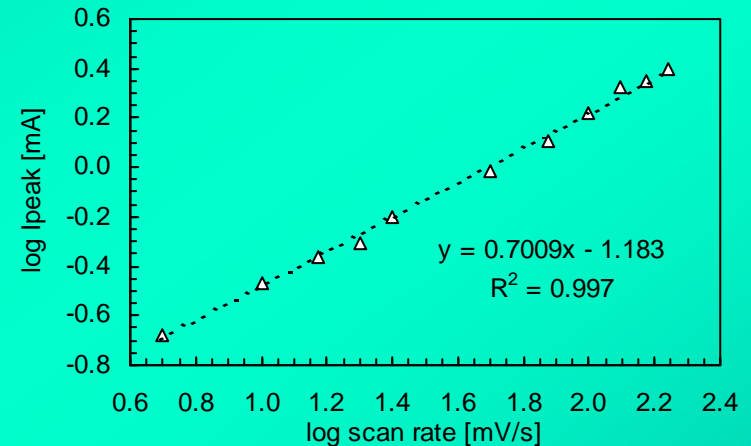
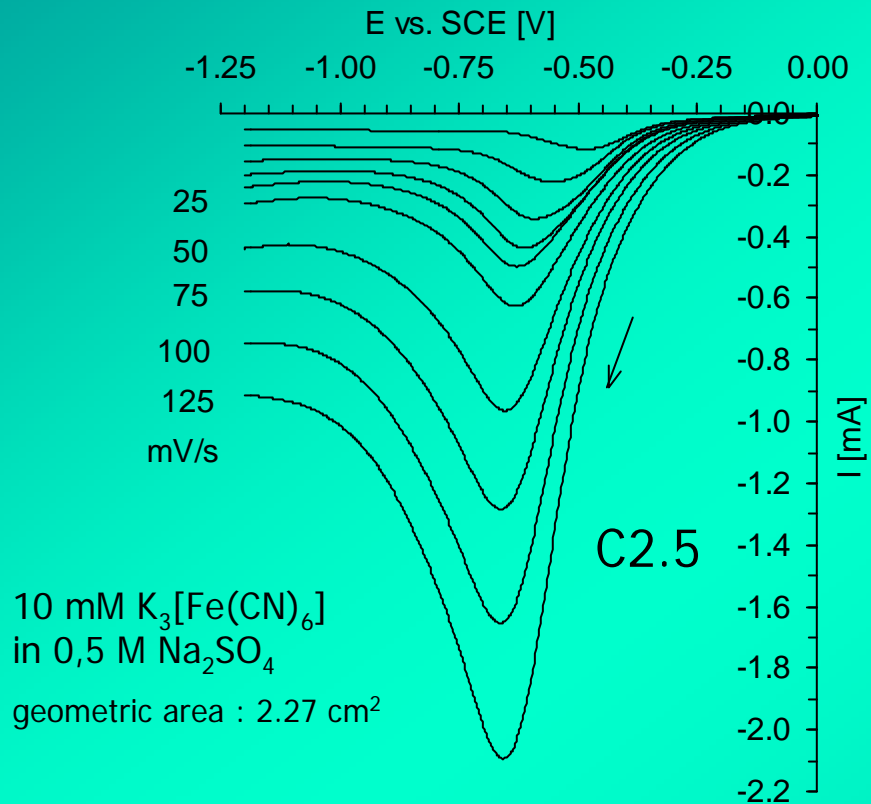
FP – fine polished, $R_a=10$ nm
Mr. Velten, University of Saarland, Germany

modification	Exponent n of the CPE
FP	0.947
P	0.927
M	0.921
G	0.890
C2.5	0.854
C6	0.874
VF	0.611
VR	0.572

$$n = \frac{1}{D_F - 1} \quad [1]$$

[1] T. PAJKOSSY, L. NYIKOS
"Impedance of fractal blocking electrodes"
J. Electrochem. Soc. 133 (10) (1986) 2061

Determination of the fractal dimension D_F by LSV measurement (reduction of ferricyanide)



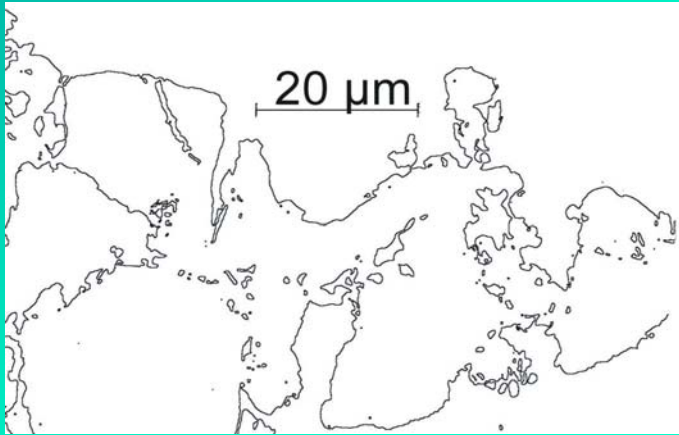
$$a = \frac{D_F - 1}{2} \quad [2]$$

[2] T. PAJKOSSY, L. NYIKOS
"Diffusion to fractal surfaces -
III. Linear sweep and cyclic voltammograms"
Electrochim. Acta 34 (2) (1989) 181-186

modification	slope a
FP	0.598
P	0.642
M	0.745
G	0.574
C2.5	0.701
C6	0.669
VF	0.889
VR	0.769

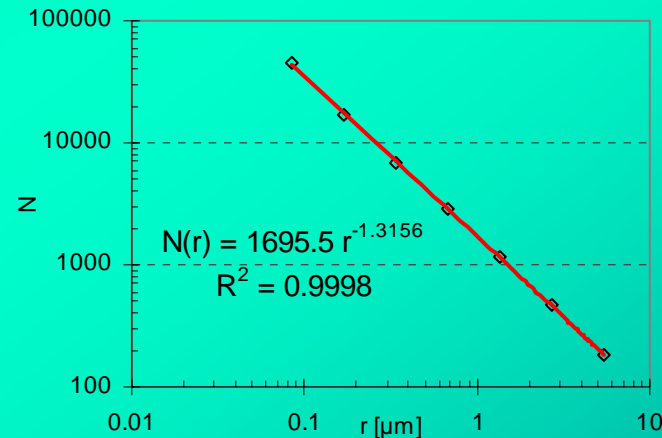
Determination of the fractal dimension D_F by Digital Image Processing (DIP)

Border line obtained from the SEM-picture of the cross section of a VF-sample



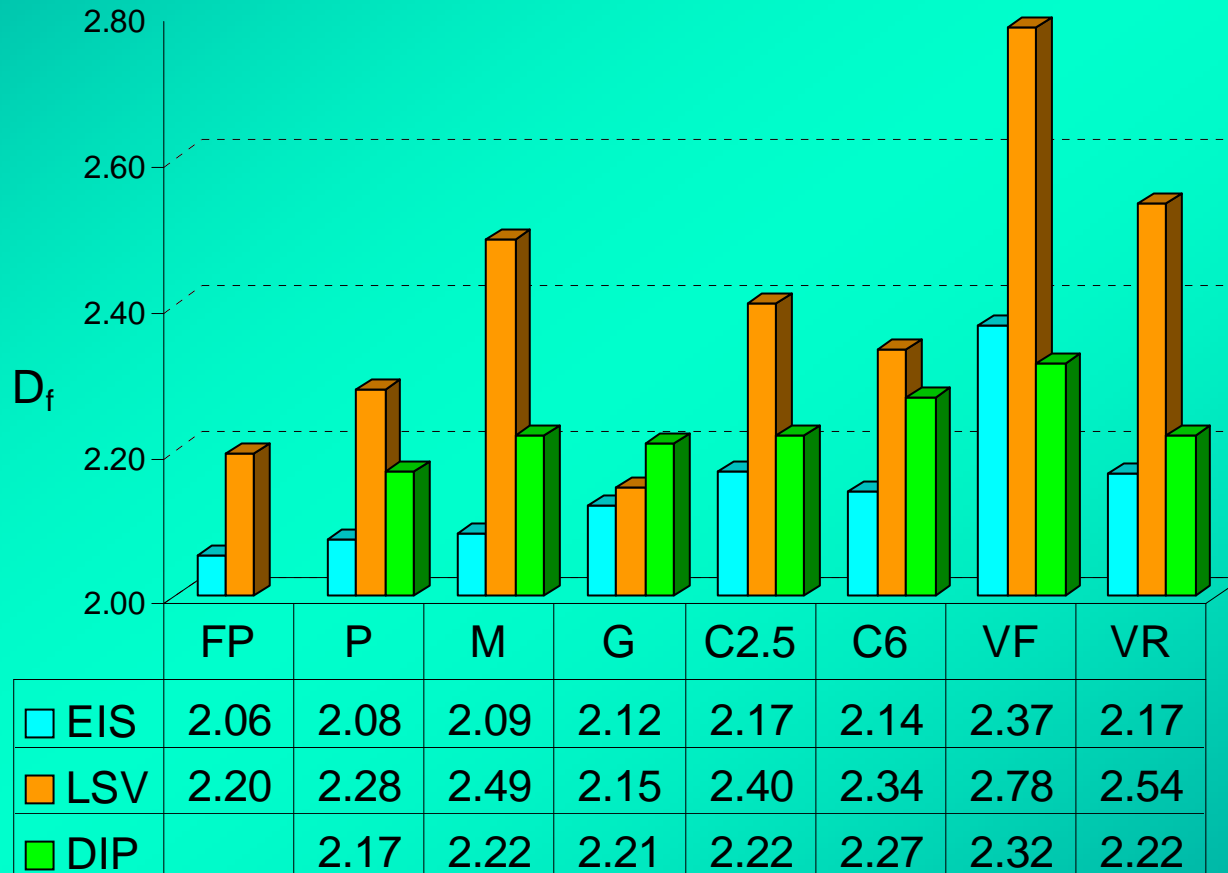
box counting algorithm
(Corel, UTHSCSA Image tool)
N - Number of boxes
r - box size
plot $\log(N) = f(\log(r))$
→ slope of the regression line
is the fractal dimension $D_{F,B}$:

Results of the box counting procedure for VF



$$N(r) = \text{const.} \cdot r^{-D_{F,B}}$$

Comparison of the fractal dimension D_F obtained by three different methods



Cell biological examinations

Expression of fibronectin in MG-63 osteoblastic cells on differently structured titanium surfaces (Western Blot)

M G VR C6 P



R_a [μm]	0.53	1.22	20.99	6.07	0.07
D_F (LSV)	2.49	2.15	2.54	2.34	2.28